

Docket No.: 1268-093A

#6 3/3/01
2872
PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

Moshe FINAROV

Serial No. 09/626,793

Filed: July 26, 2000

For: AN APPARATUS FOR INTEGRATED MONITORING OF WAFERS AND FOR
PROCESS CONTROL IN THE SEMICONDUCTOR MANUFACTURING AND A
METHOD FOR USE THEREOF



Group Art Unit: 2872

Examiner:

INFORMATION DISCLOSURE STATEMENT

Honorable Commissioner of
Patents and Trademarks
Washington, D. C. 20231

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Sir:

In accordance with the provisions of 37 C.F.R. 1.56, 1.97 and 1.98, the attention of the Patent and Trademark Office is hereby directed to the documents listed on the attached form PTO-1449. It is respectfully requested that the documents be expressly considered during the prosecution of this application, and that the documents be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

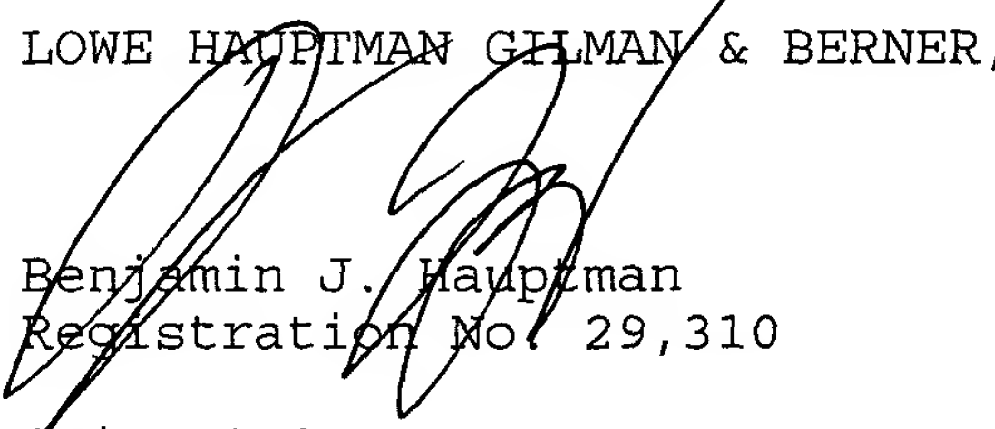
This Information Disclosure Statement is being filed within three months of the U.S. filing date OR before the mailing date of a first Office Action on the merits. No certification or fee is required.

Serial No. 09/509,080

U.S. Patent 5,604,344 is cited in the instant specification. U.S. Patent 5,682,242; Dishon et al.; "Monitoring Choices of CMP Planarization Processes", pp. 1-10, Feb. 1997; W.I.P.O. Publication no. 95/11446; an English language abstract and Japanese patent application no. 9-50959 in Japanese; and European Patent application no. 0 412 728 were cited in the specification of applicant's related co-pending Application Serial No. 09/509,070, filed May 22, 2000.

Respectfully submitted,

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No.: 1268-093

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

F. MOSHE

Serial No. 09/509,080

Filed: May 22, 2000

Group Art Unit: 2878

Examiner: Unknown

For: AN APPARATUS FOR INTEGRATED MONITORING OF WAFERS AND FOR
PROCESS CONTROL IN THE SEMICONDUCTOR MANUFACTURING AND
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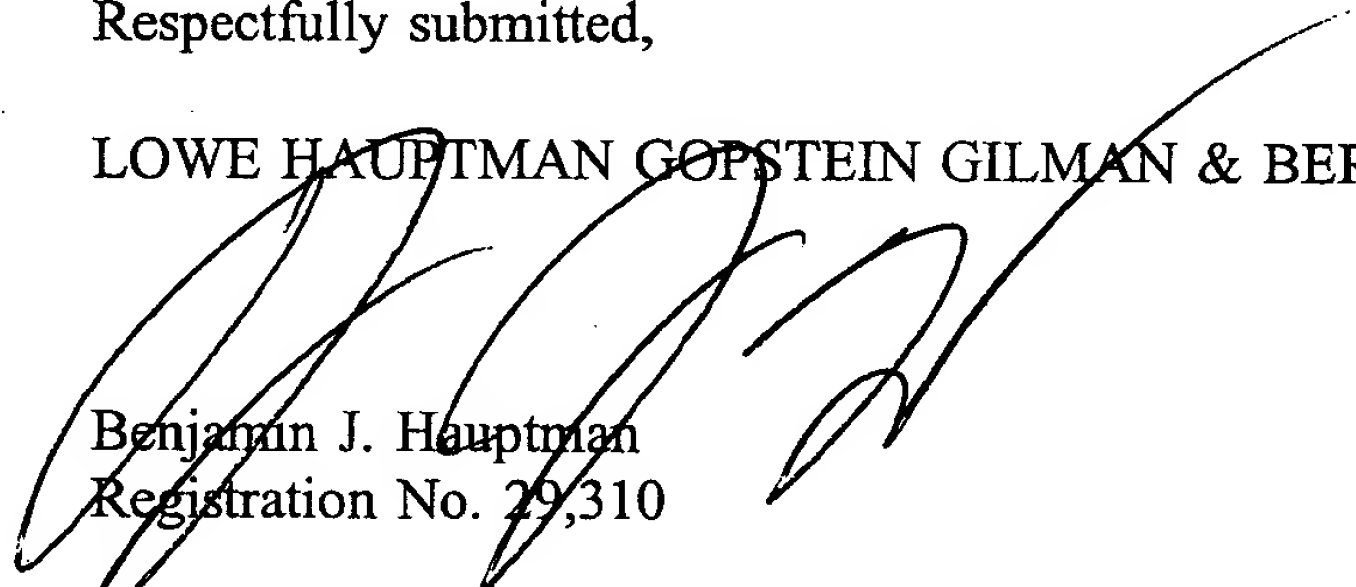
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No. 09/509,080

Each non-English language reference was cited in a corresponding foreign application search report or office action and its relevance discussed therein. A copy of the foreign search report or office action, together with an English language version thereof, is attached for the Examiner's information.

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